WaferMate200™

Robotic Wafer Handling

High Performance Wafer-Handling Platform

WAFERMATE200 IS THE MOST COST-EFFECTIVE TOOL FOR AUTOMATED STANDARD & NON-STANDARD WAFER HANDLING

The WaferMate200 is a high performance wafer-handling platform, engineered for the expert automation of semiconductor wafers and similar substrates. The standard SMEMA interface provides the most cost-effective wafer-level process solution for systems that traditionally fit a conveyor layout.

FEATURES AND BENEFITS

- Pairs seamlessly with multiple process tools.
- Configurable for two, three or four cassette positions.
- Suitable for all open cassette presentation formats.
- Accomodates film frames, 300mm open cassettes, and special thin and warped wafer components.
- Features 4-axis robots.
- Full safety guarding (OSHA and ANSI compliant).
- Suitable for 50mm to 200mm wafers, or 300mm from shipping cassette.

STANDARD ACCESSORIES

- Aligner
- Mini Environment
- OCR
- Ionization Bar
- Barcode
- Wafer Flip Module
- RFID
- Wafer Conveyor/ Oven Interface
- Cassette Tilter
- SMEMA & SECS/ GEM Interfaces

TECHNICAL SPECS

Footprint	609mm x 1244 mm	MTBF	60,000 hours
Wafer Alignment	to ± .05º	**Full SEMI Compliance**	
Wafer Placement	±100µm	**SEMI S2, S5, CE Complian**t	
Clean Room Classification	Up to ISO Class 4 (Optional)	Uptime	>97%
Wafer Interface Options	SMEMA Serial SECS/GEM Wafer Conveyor	Handling Capabilities	Thin Wafers Bonded Wafers Warped Wafers Perforated Wafers Thick Wafers Trenched Wafers Glass Wafers
Loadport Positions Available	Up to 4 x 200mm Cassettes		

For additional information, visit jabil.com/precision-automation